

U.S. Department of Commerce, Patent and Trademark Office					Atty Docket No.		Serial No.	
					M-12332 US		Unknown	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT					Applicants			
(Use several sheets if necessary)					Pablo I. Rovira and Lars Markwort			
					Filing Date		Group	
					Herewith		Unknown	
U.S. Patent Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
HP	AA	5,392,116	Feb. 21, 1995	Makosch	356	351		
HP	AB	5,502,567	Mar. 26, 1996	Pokrowsky et al.	356	367		
HP	AC	5,889,593	Mar. 30, 1999	Bareket	356	445		
HP	AD	6,002,477	Dec. 14, 1999	Hammer	356	307		
HP	AE	6,160,621	Dec. 12, 2000	Perry et al.	356	381		
HP	AF	6,122,052	Sep. 19, 2000	Barnes et al.	356	328		
HP	AG	6,275,291	Aug. 14, 2001	Abraham et al.	356	367		
	AH							
Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
HP	AI	EP 0 987 537 A2	Mar. 22, 2000	Europe				X
	AJ							
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
HP	AK	Azzram, R., "An arrangement of two reflective photodetectors for measuring all four Stokes parameters of light", <i>American Institute of Physics</i> (1991) Pages 2080-2082.						
HP	AL	Bennett, J., "Polarizers" <i>Optical Elements</i> , Chapter 3, Pages 3.1-3.70.						
HP	AM	Cumming, D. et al., "A variable polarisation compensator using artificial dielectrics" Elsevier Science (1999) Pages 164-168.						
HP	AN	Hauge, P., "Recent Developments In Instrumentation In Ellipsometry", <i>Surface Science</i> 96 (1980) Pages 108-140.						
HP	AO	Horn, T., "Liquid Crystal Imaging Stokes Polarimeter", <i>Astronomical Society of the Pacific</i> (1999) Pages 33-37.						
HP	AP	Jasperson, S., "A Modulated Ellipsometer For Studying Thin Film Optical Properties And Surface Dynamics" <i>Surface Science</i> 37 (1973) Pages 548-558.						
Examiner			Date Considered 2/20/04					
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.								

JP675 U.S. PTO  
10/02/04

12/19/01

U.S. Department of Commerce, Patent and Trademark Office						Atty Docket No.		Serial No.	
						M-12332 US		Unknown	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT						Applicants			
(Use several sheets if necessary)						Pablo I. Rovira and Lars Markwort			
						Filing Date		Group	
						Herewith		Unknown	
U.S. Patent Documents									
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate		
	AA								
	AB								
	AC								
	AD								
	AE			None					
	AF								
	AG								
	AH								
Foreign Patent Documents									
							Translation		
		Document	Date	Country	Class	Subclass	Yes	No	
	AI								
	AJ								
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)									
180	AK	Kazama, A. et al., "Compact and high-speed ellipsometer" <i>SPIE</i> Vol. 1681 Pages (1992) 183-188.							
180	AL	Lee, J. et al., "Rotating-compensator multichannel ellipsometry: Applications for real time Stokes vector spectroscopy of thin film growth", <i>Review of Scientific Instruments</i> 69 (1998) Pages 1800-1810.							
180	AM	Oliva, E., "Wedge double Wollaston, a device for single shot polarimetric measurements", <i>Astronomy &amp; Astrophysics Supplement Series</i> 123 (1977) Pages 589-592.							
180	AN	Smajkiewicz, A., "An Argument for a Filter Array vs. Linear Variable Filter in Precision Analytical Instrument Applications".							
180	AO	"Stokes Polarimetry Using Liquid-Crystal Variable Retarders", downloaded 6/11/01 from < <a href="http://www.meadowlark.com/AppNotes/appnote3.htm">http://www.meadowlark.com/AppNotes/appnote3.htm</a> >, Meadowlark Optics, Inc. (1998-2001).							
180	AP	Chapter 3, Ellipsometer Systems, "Theory and Analysis of Measurements in Ellipsometer Systems" Pages 167-268.							
Examiner		Date Considered		2/20/04					
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.									